



09-04-03

2813

PATENT

Attorney Docket No.: 002818/X1/PDD/PSI/JW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Suketu A. Parikh)
Serial No.: 09/244,788)
Confirmation No.: 4159)
Filed: 2/5/99)
For: Dual Damascene Misalignment Tolerant)
Techniques For Vias And Sacrificial)
Etch Segments)

) Group Art Unit: 2813
) Examiner: Pham, T.S.

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an **AMENDMENT AND RESPONSE** in the above-identified application, in response to the Office Action mailed 4/14/03. The fee has been calculated as shown below.

	(Col.1)		(Col.2)	(Col.3)		
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	21	MINUS	23	0	\$18.00	\$0.00
INDEPENDENT	3	MINUS	4	0	\$84.00	\$0.00
FIRST	PRESENTATION	OF	MULTIPLE DEPENDENT	CLAIM		

TOTAL . . \$0.00 . .

- ☒ No additional Filing Fee is required.
- ☒ Petition to extend time to respond.
- ☒ Extension Fee \$410.00
- ☒ The Commissioner is hereby authorized to charge \$410.00 to Deposit Account 50-1074
- ☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate of this transmittal is enclosed.

Please address all correspondence to: **PATENT COUNSEL**
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O. Box 450 A
Santa Clara, CA 95052

I hereby certify that this correspondence is being
Deposited with the United States Postal Service as
Express Mail in an envelope addressed to: Commissioner
For Patents, P.O. Box 1450, Alexandria, VA 22313-1450

Express Mail Receipt No. EV34110202USDate of Deposit SEPT, 2, 2003Signature: Emmal

Respectfully Submitted,

By:

Robert W. Mulcahy
Registration No.: 25,436

Dated: 09/02/03



#27/D/NE

PATENT

Attorney Docket No.: 002818/X1/PDD/PSI/JW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Suketu A. Parikh

Serial No.: 09/244,788

Confirmation No.: 4159

Filed: 2/5/99

For: Dual Damascene Misalignment
Tolerant Techniques For Vias And
Sacrificial Etch Segments

) Group Art Unit: 2813
) Examiner: Pham, T.S.
)
) Amendment and Response to Office
) Action Mailed 4/14/03
)
) PATENT COUNSEL
) APPLIED MATERIALS, INC.
) Legal Affairs Department
) P.O. Box 450 A
) Santa Clara, CA 95052
)

10/28/03
Adm th

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SEP - 8 2003
TECHNOLOGY CENTER 2800

Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE

RECEIVED
SEP 12 2003
TC 1700

This response concerning the above-identified application is in response to the Office
Action mailed on April 14, 2003.